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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KATSUMATA et al.

Atty. Dkt.: 01-570

Serial No.: 10/791,762

Art Unit: 2812

Filed: 3/4/2004

Examiner: TSAI

Title: METHOD OF MANUFACTURING
SEMICONDUCTOR PRESSURE SENSOR

Commissioner for Patents
U.S. Patent and Trademark Office
220 20th Street S.
Customer Window, Mail Stop Amendment
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Date: 28 October 2004

AMENDMENT UNDER 37 CFR 1.111

Sir:

In response to the office action mailed 28 October 2004, please consider as follows:

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks begin on page 5 of this paper.